## INTERNATIONAL SEARCH REPORT

International Application No PCT/DK 03/00372

A. CLASSIFICATION OF SUBJECT MATTER IPC 7 B81C1/00 B81B7/00 According to International Patent Classification (IPC) or to both national classification and IPC B. FIELDS SEARCHED Minimum documentation searched (classification system followed by classification symbols) IPC 7 B81B B81C GO3B Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched Electronic data base consulted during the international search (name of data base and, where practical, search terms used) INSPEC, EPO-Internal, WPI Data, PAJ C. DOCUMENTS CONSIDERED TO BE RELEVANT Category ° Citation of document, with indication, where appropriate, of the relevant passages Relevant to claim No. γ ZHIHONG LI ET AL: "An SOI-MEMS technology using substrate layer and bonded glass as 1 - 39wafer-level package" SENSORS AND ACTUATORS A (PHYSICAL), 31 JAN. 2002, ELSEVIER, SWITZERLAND, vol. A96, no. 1, pages 34-42, XP002264165 ISSN: 0924-4247 abstract; figure 1 Υ RAVNKILDE, J.T. ET AL: "Fabrication of nickel microshutter arrays for spatial 1-39 light modulation." PROCEEDINGS OF THE 4TH MESO MECHANICS CONFERENCE, August 2002 (2002-08), pages 1 -5, XP002264166 Aalborg, Denmark abstract; figure 1 -/--X Further documents are listed in the continuation of box C. Patent family members are listed in annex. Special categories of cited documents: "T" later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the "A" document defining the general state of the art which is not considered to be of particular relevance "E" earlier document but published on or after the international "X" document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to filing date "L" document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified) involve an inventive step when the document is taken alone "Y" document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled "O" document referring to an oral disclosure, use, exhibition or other means "P" document published prior to the international filing date but later than the priority date claimed "&" document member of the same patent family Date of the actual completion of the international search Date of mailing of the international search report 8 December 2003 2 9. 12. 2003 Name and mailing address of the ISA Authorized officer European Patent Office, P.B. 5818 Patentlaan 2 NL - 2280 HV Rijswijk Tel. (+31-70) 340-2040, Tx. 31 651 epo nl, Fax: (+31-70) 340-3016 DANIEL MOE

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C.(Continu	ation) DOCUMENTS CONSIDERED TO BE RELEVANT	PCT/DK 03/00372	
Category °		Relevant to claim No.	
A	US 2002/081821 A1 (RIDLEY JEFFREY ALAN ET AL) 27 June 2002 (2002-06-27) figures 4A-4C abstract	1-39	
Α	CHENG Y -T ET AL: "A hermetic glass-silicon package formed using localized aluminum/silicon-glass bonding" JOURNAL OF MICROELECTROMECHANICAL SYSTEMS, SEPT. 2001, IEEE, USA, vol. 10, no. 3, - 2001 pages 392-399, XP002264167 ISSN: 1057-7157 abstract; figure 1	1-39	
A	WO 99 10775 A (MEMS OPTICAL INC) 4 March 1999 (1999-03-04) abstract; figures 1,2	1-39	
	JAECKLIN V P ET AL: "Optical microshutters and torsional micromirrors for light modulator arrays" PROCEEDINGS. IEEE. MICRO ELECTRO MECHANICAL SYSTEMS. AN INVESTIGATION OF MICRO STRUCTURES, SENSORS, ACTUATORS, MACHINES AND SYSTEMS (CAT. NO.93CH3265-6), PROCEEDINGS OF MICRO ELECTRO MECHANICAL SYSTEMS, FORT LAUDERDALE, FL, USA, 7-10 FEB. 1993, pages 124-127, XP002264168 1993, New York, NY, USA, IEEE, USA ISBN: 0-7803-0957-X abstract; figure 1	1-39	
	LARSEN, K.P. ET AL: "SOI silicon on glass for optical MEMS" TRANSDUCERS, SOLID-STATE SENSORS, ACTUATORS AND MICROSYSTEM 12TH INTERNATIONAL CONFERENCE, 9 - 12 June 2003, pages 1655-1658, XP002264169 the whole document	1-39	

Form PCT/ISA/210 (continuation of second sheet) (July 1992)

## INTERNATIONAL SEARCH REPORT

Information on patent family members

International Application No PCT/DK 03/00372

Patent document cited in search report		Publication date	Patent family member(s)		Publication date
US 2002081821	A1	27-06-2002	EP TW WO	1345844 A2 521060 B 02057180 A2	24-09-2003 21-02-2003 25-07-2002
WO 9910775	Α	04-03-1999	AU WO US US	9124298 A 9910775 A1 6214633 B1 2001000491 A1	16-03-1999 04-03-1999 10-04-2001 26-04-2001

Form PCT/ISA/210 (patent family annex) (July 1992)